ME 237: Mechanics of Microsystems : Lecture



# Modeling Squeeze Film Effects in MEMS

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Introduction Motivation SF in MEMS

Modeling Solution Methods Results Interpretation

Summary

- Introduction : What is Squeeze Film and when does it occur?
- Motivation: Why is it important to study?
- Various MEMS devices showing Squeeze Film Effects
- Modelling : The Reynolds Equation
- Solution Methods
- The Eigen-expansion Method
- Understanding the Results
- Summary

## Introduction : What is Squeeze Film Effect

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### Schematic of Squeeze flow\*



\* Animation courtesy : Siddartha Patra, ME 2011, Mechanical Engineering, IISC Bangalore

### Introduction : Squeeze Flow

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# Introduction : Relevant Conditions for Squeeze Film Effects

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\* Animation (MEMS Tuning Gyro)Courtesy JP Reddy, CeNSE, IISC

# Motivation: Importance of squeeze film

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# Change in effective stiffness and Damping \*

$$m_{\rm eq}\ddot{x} + (C_{\rm eq} + C_{\rm sq})\dot{x} + (K_{\rm eq} + K_{\rm sq})x = F_0\sin(\omega t)$$



## Squeeze Film in MEMS devices

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### Getting to the Reynolds Equation

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Under continuum hypothesis fluid flow is modelled using the Navier Stoke's Equation

$$\rho \frac{Du_i}{Dt} = -\frac{\partial p}{\partial x_i} + \rho g_i + \frac{\partial}{\partial x_j} \left[ 2\mu e_{ij} - \frac{2}{3}\mu (\boldsymbol{\nabla} \cdot \mathbf{u})\delta_{ij} \right]$$
 1

Assuming small temperature differences within fluid ' $\mu$ ' can be treated as constant and we can rewrite (1) as

$$\rho \frac{Du_i}{Dt} = -\frac{\partial p}{\partial x_i} + \rho g_i + \mu \left[ \nabla^2 u_i + \frac{1}{3} \frac{\partial}{\partial x_i} (\nabla \cdot \mathbf{u}) \right]$$
 (2)

Assuming **incompressible** flow we get from equation (2)

$$\nabla \cdot \mathbf{u} = 0,$$

$$\rho \frac{D\mathbf{u}}{Dt} = -\nabla p + \rho \mathbf{g} + \mu \nabla^2 \mathbf{u}.$$



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### Navier Stokes

$$\rho \left( \frac{\partial w}{\partial t} + u \frac{\partial y}{\partial x} + v \frac{\partial w}{\partial y} + w \frac{\partial u}{\partial z} \right) = \rho x - \frac{\partial p}{\partial x} + \mu \left( \frac{\partial^2 w}{\partial x^2} + \frac{\partial^2 u}{\partial y^2} + \frac{\partial^2 u}{\partial z^2} \right)$$

$$\rho \left( \frac{\partial v}{\partial t} + u \frac{\partial y}{\partial x} + v \frac{\partial w}{\partial y} + w \frac{\partial v}{\partial z} \right) = \rho x - \frac{\partial p}{\partial y} + \mu \left( \frac{\partial^2 v}{\partial x^2} + \frac{\partial^2 v}{\partial y^2} + \frac{\partial^2 v}{\partial z^2} \right)$$

$$\rho \left( \frac{\partial w}{\partial t} + v \frac{\partial w}{\partial x} + v \frac{\partial w}{\partial y} + w \frac{\partial w}{\partial z} \right) = \rho x - \frac{\partial p}{\partial z} + \mu \left( \frac{\partial^2 w}{\partial x^2} + \frac{\partial^2 w}{\partial y^2} + \frac{\partial^2 w}{\partial z^2} \right)$$

$$P \left( \frac{\partial w}{\partial t} + v \frac{\partial w}{\partial y} + w \frac{\partial w}{\partial z} \right) = \rho x - \frac{\partial p}{\partial z} + \mu \left( \frac{\partial^2 w}{\partial x^2} + \frac{\partial^2 w}{\partial y^2} + \frac{\partial^2 w}{\partial z^2} \right)$$
Neglect Body forces
$$Neglect fluid inertia$$

$$Thin Film thickness$$

$$Small am.p of Osc.$$

$$Fully Developed flow$$



\* Source [2]

## The Reynolds Equation

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$$\frac{\partial}{\partial x} \left( \frac{ph^3}{\mu} \frac{\partial p}{\partial x} \right) + \frac{\partial}{\partial y} \left( \frac{ph^3}{\mu} \frac{\partial p}{\partial y} \right) = 12 \frac{\partial (ph)}{\partial t}.$$

$$\left[\frac{\partial^2 \hat{p}}{\partial x^2} + \frac{\partial^2 \hat{p}}{\partial y^2}\right] = \frac{12\mu}{P_a h_a^3} \left[h_a \frac{\partial \hat{p}}{\partial t} + P_a \frac{\partial \hat{h}}{\partial t}\right]$$

 $\begin{bmatrix} \frac{\partial^2 \Phi}{\partial X^2} + \frac{\partial^2 \Phi}{\partial Y^2} \end{bmatrix} = \sigma \begin{bmatrix} \frac{\partial \Phi}{\partial \tau} + \frac{\partial \epsilon}{\partial \tau} \end{bmatrix}$ Squeeze Number

Nonlinear compressible Reynolds Equation

Linearized compressible Reynolds Equation

Linearized Non dimensional compressible Reynolds Equation

## The Squeeze number

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# Analytical Techniques for solution of Reynolds Equation

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Based on – **28 papers** surveyed



### Separation of Variables : Eigen Expansion

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We are solving linearized Reynolds eqn.

Consider homogeneous form of (1)

Using eigen expansion and separation of variables we assume

Where

$$\nabla^2 P - \alpha^2 \frac{\partial P}{\partial t} = \alpha^2 \frac{\partial H}{\partial t} \quad --- \quad (1)$$

$$P = u(x, y, t) \tag{3}$$

$$u = \sum_{m,n} f(x,y)_{mn} T(t) \tag{4}$$

Thus from (2), (3), and 4 we get

Now assume the following

$$\frac{\nabla^2 f}{f} = \frac{\alpha^2 \frac{\partial T}{\partial t}}{T} = -k_{mn}^2 \qquad (5)$$

$$k_{mn}^2 = k_m^2 + k_n^2 \tag{6}$$

$$f_{mn} = a_{mn}\psi_{mn}(x,y) \tag{7}$$



 $\sum_{m,n} -a_{mn}k_{mn}^2\psi_{mn}(x,y)e^{i\omega t} - a_{mn}\alpha^2\psi_{mn}(x,y)i\omega e^{i\omega t} = \delta\phi e^{i\omega t}$ (11)

Multiplying both sides of (11) by

$$\psi_{pq}(x,y) \tag{12}$$

And using orthogonality 
$$\int \int \psi_{mn}(x,y)\psi_{pq}(x,y)dxdy = \delta_{mn}\delta_{pq} \quad (13)$$

## Solution: Contd.

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We get  $a_{mn} = \delta \frac{\int_{0}^{L} \int_{0}^{W} i\omega}{\frac{L}{W}}$ 

$$nn = \delta \frac{\int \int i\omega \alpha^2 \phi \psi_{mn} dy dx}{\int \int \int \int \int [-k_{mn}^2 - i\omega \alpha^2] \psi_{mn}^2 dy dx}$$
(14)

1 1

2 1 1

Now the first mode shape of the plate can be approximated as

$$\phi(x,y) = \sin\left(\frac{\pi x}{L}\right)^2 \sin\left(\frac{\pi y}{W}\right)^2 - (15)$$

Thus the solution is given by (8) 
$$P = \sum_{m,n} a_{mn} \psi_{mn}(x,y) T(t)$$

Where $\psi_{mn}(x,y)$ Is an admissible eigen functionOpen<br/>Boundary $\longrightarrow$ P = 0Closed<br/>Boundary $\longrightarrow$  $\frac{\partial P}{\partial n} = 0$ 



 $\phi_{xx}(x,y) < 0$ 

## Admissible Eigen Function s: 0000

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From separation of variables for P

$$\nabla^2 \psi_{mn} + k_{mn}^2 \psi_{mn} = 0$$

$$\psi_{mn}(x, y) = X_m(x)Y_n(y)$$
$$k_{mn}^2 = k_m^2 + k_n^2$$

We get

Assuming

$$X_m''Y_n + X_mY_n'' + k_{mn}^2 X_m Y_n = 0$$

Separating variables we get the x and y equations

Applying zero pressure BCs, we get

$$X_m = A\sin(k_m x) + B\cos(k_m x)$$
$$Y_n = C\sin(k_n x) + D\cos(k_n x)$$
$$\psi_{mn}(x, y) = \sin\left(\frac{m\pi x}{L}\right)\sin\left(\frac{n\pi y}{W}\right)$$

# Solution for the All sides open case : 0000

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All sides open

Zero pressure B.C.'s

$$P(0,y) = P(L,y) = 0$$

P(x,0) = P(x,W) = 0

Admissible eigen function

$$\psi_{mn}(x,y) = \sin\left(\frac{m\pi x}{L}\right)\sin\left(\frac{n\pi y}{W}\right)$$

And using  

$$\phi(x,y) = \sin\left(\frac{\pi x}{L}\right)^2 \sin\left(\frac{\pi y}{W}\right)^2 \quad \text{with}$$

$$P = \sum_{m,n} a_{mn} \psi_{mn}(x,y) T(t) \quad \text{in} \quad a_{mn} = \delta \frac{\int_{0}^{L} \int_{0}^{W} i\omega \alpha^2 \phi \psi_{mn} dy dx}{\int_{0}^{L} \int_{0}^{W} [-k_{mn}^2 - i\omega \alpha^2] \psi_{mn}^2 dy dx}$$
with  $T(t) = e^{i\omega t}$ 

### Solution for the All sides open case : 0000

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# Results : Stiffness and Damping Relative comparison among flow BCs



# Results : Pressure and Phase variation: OOCC

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0.8

0.6

0.4

0.2

°0



Phase variation : a)  $\sigma = 0.1$ , b)  $\sigma = 1000$ 



0000



# Pressure Profiles varying with Squeeze number

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#### 0000





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### Summary

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- We have seen when and where squeeze film effects occur.
- We discussed modeling aspects and solution methods.
- Variation of squeeze film parameters with squeeze number was shown.
- Effect of flow boundary conditions were discussed.
- Pressure and phase variation with squeeze number were shown.

#### Other aspects in squeeze film modeling

Complexities	Coupled Domains	Commercial Software for Modeling Squeeze
Rarefaction	Structural	Film
Compressibility	Fluid	
Inertia	Electrostatic	ANSYS
Perforations		COMSOL
Non trivial BC's		NISA
<b>Complex</b> geometries		

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- 4. Ahmad B and Pratap R (2011) Analytical evaluation of squeeze film forces in a CMUT with sealed air filled cavity. IEEE Sensors 11(10): 2426-2431.
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- 6. Pandey A (2007) Analytical, Numerical, and Experimental Studies of Fluid Damping in MEMS Devices. PhD Thesis: Indian Institute of Science, Bangalore, India.
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# Help Slides

# Losses in MEMS devices



given as :

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# **Definitions and Basic Terminology**

# Number Density of molecules (n)



P = Pressure  $K_b$  (Boltzmann Const) = 1.3805 x 10<sup>23</sup> T = Temperature

#### Under standard conditions

P = 1.013 x 10<sup>5</sup> Pa (1 atm ) T = 273.15 K n = 2.69x 10<sup>25</sup> x m<sup>-3</sup>

### Molecular diameter(d)

Under STP using Hard sphere model d~ 3.7 x 10<sup>-10</sup> m Mean Free Path  $\lambda$ 

$$=\frac{1}{\sqrt{2}\pi d^2 n}$$

Average distance travelled by a molecule between two successive collisions

 $\lambda$ 

#### Under ambient conditions

T = 300 K d~ 3.7 x  $10^{-10}$  m n = 2.41x  $10^{20}$  x P m<sup>-3</sup>  $\lambda$  = 0.0068/P and for P = 1.013 x  $10^5$  Pa (1 atm)  $\lambda$  = 67 nm

### Characteristic flow length (h)

Characteristic length of the flow channel in case of Squeeze film it is the gap thickness

# Effective Viscosity\*

Author	Reference	Effective Viscosity ( $\mu^*$ )	Derived from
Burgdorfer	1959 [17]	$\frac{\mu}{1+6K_n}$	Navier-Stokes equation
Hsia et al.	1983 [18]	$\frac{\mu}{1+6K_n+6K_n^2}$	Experimental data fitting
Fukui et al.	1988 [19]	$\frac{D}{6Q(D)} ; D = \frac{\sqrt{\pi}}{2K_n}$	Boltzmann equation
Seidel et al.	1993 [6]	$\frac{0.7\mu}{K_n}$	Experimental data fitting
Mitsuya	1993 [20]	$\frac{\mu}{1+6\left(\frac{2-\alpha}{\alpha}\right)K_n+\frac{8}{3}K_n^2}$	Navier-Stokes equation
Veijola et al.	1995 [8]	$\frac{\mu}{1+9.638K_n^{1.159}}$	Approximation of Fukui's model
CL Chen	1996 [21]	$\frac{\mu}{1+6\alpha K_n}$	Navier-Stokes equation

\* MS Thesis, J Young, Massachusetts Institute of Technology, 1998

# Vector Diagram – Force and Displacement\*

- F=∫PdA
- F= || F || exp(i (ωt-φ))
- Fs= || F || cos(φ)
- Fd= || F || sin(φ)
- Ksq=Fs/δh
- Csq=Fs/δh/ ω



\* Slide courtesy S Patra

# **Discussion – Analytical**

We have  $\nabla^2 P - \alpha^2 \frac{\partial P}{\partial t} = \alpha^2 \frac{\partial H}{\partial t}$   $P = \sum_{m,n} a_{mn} \psi_{mn}(x, y) T(t)$   $\nabla^2_{X,Y} \tilde{P} - i\sigma \tilde{P} = \frac{\partial^2 \tilde{P}}{\partial X^2} + \frac{\partial^2 \tilde{P}}{\partial Y^2} - i\sigma \tilde{P} = i\sigma \delta \psi$   $P = \tilde{P} e^{i\omega t}$ For low  $\sigma$   $i\sigma \tilde{P}$ 

• Is negligible resulting in differential pressure to be small and out of phase 90° with displacement

For high  $\boldsymbol{\sigma}$   $i\sigma\tilde{P}$ 

• Is dominant term and pressure profile approximately matches displacement profile and pressure profile is +- 180° out of phase with displacement